

Title (en)

MEASURING DEVICE AND MEASURING METHOD FOR INSPECTING THE SURFACE OF A SUBSTRATE

Title (de)

MESSVORRICHTUNG UND MESSVERFAHREN ZUM INSPIZIEREN EINER OBERFLÄCHE EINES SUBSTRATES

Title (fr)

DISPOSITIF ET PROCÉDÉ DE MESURE POUR INSPECTER UNE SURFACE D'UN SUBSTRAT

Publication

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Application

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Abstract (en)

[origin: WO2008058869A2] The invention relates to a measuring device (100) for inspecting the surface (141) of a substrate (140). The measuring device (100) has a retaining element (110) and an air-mounted element (120, 220), which is fixed to the retaining element (110), the air-mounted element being designed in such a way that an air bearing can be formed together with the surface (141) of the substrate (140) to be inspected and having an elasticity that enables the air-mounted element (120, 220) to be adapted to any irregularities in the surface (141). The measuring device (100) also has at least one sensor (130, 230), which is fixed to the air-mounted element (120, 220) and which is configured to record the surface (141) of the substrate (140). As a result of the flexibility of the air-mounted element (120, 220), the sensor or sensors (130, 230) can be displaced at a constant measuring distance from the surface (141) to be inspected even if said surface (141) undulates. The invention also relates to a measuring method for inspecting surfaces, according to which the measuring device (100) is displaced in relation to the surface (141).

IPC 8 full level

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Citation (search report)

See references of WO 2008058869A2

Citation (examination)

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